



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
YOSHIKATSU ICHIMURA, et al.) Examiner: Marina Kramskaya
Application No.: 10/550,450) Group Art Unit: 2858
Int'l App No.: PCT/JP04/04343)
Int'l Filing Date: March 26, 2004)
For: ELECTRIC POTENTIAL)
MEASURING DEVICE AND)
IMAGE FORMING APPARATUS) October 17, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed below on the enclosed Form PTO-1449. Copies of documents (7) to (15) are enclosed.

- (1) U.S. Patent No. 4,205,267
- (2) U.S. Patent No. 5,212,451
- (3) U.S. Patent No. 5,504,356

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on:

October 17, 2006
(Date of Deposit)

John D. Magluyan, Reg. No. 56,867
(Name of Attorney for Applicants)


Signature _____ Date of Signature _____
October 17, 2006

- (4) U.S. Patent Application Publication No. 2003/0057977
- (5) U.S. Patent Application Publication No. 2006/0171728
- (6) U.S. Patent Application Publication No. 2006/0192565
- (7) DE 2715831
- (8) DE 10044887
- (9) EP 1003044
- (10) JP 2-071166
- (11) JP 4-025764
- (12) JP 6-196721
- (13) JP 6-196722
- (14) HSU C. H. et al: "Micromechanical electrostatic voltmeter" "TRANSDUCERS. SAN FRANCISCO, JUNE 24-27, 1991, PROCEEDINGS OF THE INTERNATIONAL CONFERENCE ON SOLID STATE SENSORS AND ACTUATORS, NEW YORK, IEEE, US, vol. CONF. 6, 24 JUNE 1991 (1991-06-24), pages 659-662
- (15) RIEHL P.S. "Microsystems for Electrostatic Sensing" DISSERTATION, Online! November 2002 (2002-11) Page 1-8, 32-40, 79-84
<http://www-bsac.eecs.berkeley.edu/publications/search/zoom.php?urltimestamp=1040564878>.

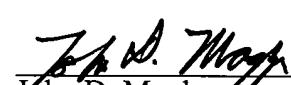
English language abstracts accompany each of documents (8) and (10) to (13). Additionally, it is noted that document (3) is an English-language counterpart for both of documents (12) and (13). The concise explanation of relevance for each of non-English language documents (8) and (10) to (13) is believed to be satisfied by the English language abstracts and the English language counterpart. See MPEP § 609.

The subject application has received an Office Action on the merits but has not yet received either a final action or a Notice Of Allowance. Accordingly, this Information Disclosure Statement is filed under 37 C.F.R. § 1.97(c) and is accompanied by the \$180.00 fee specified at 37 C.F.R. § 1.17(p). Consideration of the art cited herein is accordingly deemed proper, and such action is respectfully requested. Additionally, the Examiner is requested to indicate that this information has been considered by initialling

the appropriate portion of Form PTO-1449 and returning the initialed form to Applicants with the next communication.

Applicants' undersigned attorney may be reached in our Costa Mesa, California office by telephone at (714) 540-8700. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



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FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. 03500.017986.		APPLICATION NO. 10/550,450		
			APPLICANT YOSHIKATSU ICHIMURA, et al.				
			FILING DATE September 26, 2005		GROUP 2858		
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		4,205,267	05/1980	Williams	324	458	
		5,212,451	05/1993	Werner, Jr.	324	458	
		5,504,356	04/1996	Takeuchi, et al.	257	254	
		2003/0057977	03/2003	Werner, Jr., et al.	324	754	
		2006/0171728	08/2006	Ichimura, et al.	399	48	
		2006/0192565	08/2006	Yasuda, et al.	324	458	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		2715831	10/1978	Germany			No
		10044887	05/2001	Germany			Abstract
		1003044	05/2000	Europe			
		2-071166	03/1990	Japan			Abstract
		4-025764	01/1992	Japan			Abstract
		6-196721	07/1994	Japan			Abstract
		6-196722	07/1994	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		HSU C. H. et al: "Micromechanical electrostatic voltmeter "TRANSDUCERS. SAN FRANCISCO, JUNE 24-27, 1991, PROCEEDINGS OF THE INTERNATIONAL CONFERENCE ON SOLID STATE SENSORS AND ACTUATORS, NEW YORK, IEEE, US, vol. CONF. 6, 24 JUNE 1991 (1991-06-24), pages 659-662					
		RIEHL P.S. "Microsystems for Electrostatic Sensing" DISSERTATION, Online! November 2002 (2002-11) Page 1-8, 32-40, 79-84 (http://www-bsac.eecs.berkeley.edu/publications/search/zoom.php?urltimestamp=1040564878)					
EXAMINER			DATE CONSIDERED				

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 1